

Notice of References Cited

Application/Control No.

08/636,069

Applicant(s)/Patent Under
Reexamination
SANDHU ET AL.

Examiner

Erik Kielin

Art Unit

2813

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,166,101 /	11-1992	Lee et al.	438/763
	B	US-			
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	D	US-			
	E	US-			
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	K	US-			
	L	US-			
	M	US-			

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	N	EP 0 562 625 A2 /	03-1993	EPO	Imai et al.	--
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NON-PATENT DOCUMENTS

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	U	Pierson, Handbook of Chemical Vapor Deposition, Noyes Publications: Park Ridge, New Jersey, 1992, pp.26-27.
	V	Translation of JP 2-050966 (Hisamune, Yoshiaki).
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.